

Process:	DCS-HTO
Equipment ID	DF-OHT-02
Model	Alpha-303i
Item	Detail
General Configuration	
Process	DCS-HTO
Tool Mode	Alpha-303i
OEM Serial #	L000005X5343
Safety Specification	S2-0200 / CE-Mark(STD)
Shipping Area	Asia
Host Communications	Comply with GJG (STD)
PIO I/F Connection	FNC Top (OP)
Automated Material Handling System	OHT (OP)
PGV Operation	None
Equipment Host I/F Connection	Gas Box Top (OP)
Group Controller	AGC (OP)
External I/F	Pending
FTP	Yes (OP)
WAVES Version	Latest Version
Indicator	TEL Standard (Superset)
Side Maintenance	None (STD)
System Paint Color	White(STD)
Process Pressure	33Pa
Process Temperature (C)	830C
Heater Type	Mid-Temp. VMM-56-002 5zone / 500-1000 (C)
N2 Purge System	Installed (OP) without dewpoint meter
Boat Operation	2 Boats Type
Carrier I/D Reader/Writer	Read (at Load Port) / Write (at Load Port) (OP)
Type	RF (OP)
Maker/Model	ASYST / ATR9100
Provider	TEL
Warning Label	Traditional Chinese / English
Gas Distribution System	
Basic Style	Integrated Gas System (STD)
Tubing	Stainless Steel / Electrical-polish (STD)

Tubing Bends	No Bend (OP)
Tube Heating (Include Vacuum Line)	Use
Manual Valve	Fujikin
Air-Operated Valve	Fujikin
Filter	MYKROLIS
Regulator	VERIFLO
MFC (Gas Panel)	AE
Press. Transducer	MYKROLIS
Soft Backfill Injector	Installed (OP)
Manifold Heater	Not Use
Liquid Source Operation System	None
Liquid Source Auto-Refill	None (STD)
Auto-Refill Provided By	N/A
Auto-Refill Tubing Interconnect By	N/A
Gas System Schem. Dwg / Parts List	2192-349531-1*
Vacuum System	
Vacuum Exhaust System	New Type
Pump	KASHIYAMA 30000L/min
Pump Provided by	Customer
Pump Power	Customer's Facility Provided
N2 Gas Panel for Pump Provided By	Customer
Pump-FNC Vac Tubing Provided By	Customer (STD)
Vacuum Pressure Controller	CKD VEC
Vacuum Gage - Pressure Ctrl	MKS (Hot) Capacitance Manometer
Vacuum Gage - Press. Monitor(133kPa)	MKS (Hot) Capacitance Manometer
Vacuum Gage - Pump Monitor	MKS Capacitance Manometer
Main Valve	CKD VEC
Trap	Not Installed
Wafer/Carrier Handling	
Wafer Type	300 SEMI STD-Notch
Wafer Notch Aligner	Not Installed (STD)
Carrier Type	FOUP / 25slots (STD)
Carrier Maker/Type	Pending
Carrier Storage Qty.	16
Fork Type/Material	1+4 / Al2O3 (STD)
W/T Wafer I/F speed(U/D)	Standard
Wafer Loading/Unloading Sequence	ED-->P-->M / M-->P-->ED
Cap Heater	Not Use
Boat / Pedestal	
Qty. of Production Wafers	75
Boat Material	Quartz

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Boat Type	86 slots Ladder (11mm pitch)
Boat Rotation	Installed
Pedestal Type	Quartz +SiC
Process Tube	
Outer / Inner Tube Material	Quartz/Quartz
Inner Type	Reduce(ID384-ID354)
Internal T/C Type	Outer Tube interior wall type (for CONV.)
Tube Sealing	O-ring Seal
Quartzware - General	
Quartz Maker Requirement	None
Quartz Provider	See Customized Details
SIC Maker Requirement	None
SIC Provider	Customer

